

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

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10/650,729

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Chung-Peng HO, et al.

FILING DATE

August 29, 2003

GROUP

1756

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
ND	AA	5,986,742	11/16/99	Straaljer et al.			
ND	AB	2002/0163629	11/7/02	Switkes et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AO					
	AP					
	AQ					
	AR					
	AS					
	AT					
	AU					
	AV					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

ND	AW	Owen et al., "1/8 μ m optical lithography," Journal of Vacuum Science and Technology, B 10(6), 3032-3036 (1992).
ND	AX	Switkes et al., "Immersion lithography at 157 nm," Journal of Vacuum Science and Technology, B 19(6), 2353-2356 (2001).
ND	AY	Hoffnagle et al., "Liquid Immersion deep-ultraviolet Interferometric lithography," Journal of Vacuum Science and Technology, B 17(6), 3306-3309 (1999).
	AZ	

☐ Additional References sheet(s) attached

Examiner

David H. H. H. H.

Date Considered 09/17/2005

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.